

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
CEM BASCERI ET AL.

Assignee: Micron Technologies

Serial No.: unknown

Filed: August 29, 2002

For: Micromachines for Delivering Precursors
and Gases for Film Deposition

§ Group Art Unit: unknown
§
§ Examiner: unknown
§
§ Examiner phone: unknown
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§ Atty. Dkt. No.: 102-0075US-3
§
§
§
§

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56, it is respectfully requested that this Information Disclosure Statement be entered and the documents listed on the attached Form PTO-1449 be considered by the Examiner and made of record.

In accordance with 37 C.F.R §§ 1.97(g),(h), this Information Disclosure Statement should not be construed as a representation that a search has been made, and is not to be construed to be an admission that the information cited is prior art or is considered to be material to patentability as defined in 37 C.F.R. § 1.56(b).

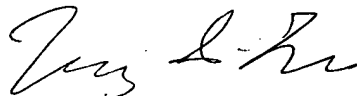
This Information Disclosure Statement is being filed prior to the receipt of a first Office Action reflecting an examination on the merits, and hence is believed to be timely in accordance with 37 C.F.R. § 1.97(b). Accordingly, no fee is believed to be due. Should any fees be deemed

necessary, however, the Commissioner is hereby authorized to charge any such fees to Deposit Account No. 501922.

This application is a divisional application of Serial No. 10/230,874, filed on August 29, 2002, and is relied upon for an earlier filing date under 35 U.S.C. § 120. In accordance with 37 C.F.R. § 1.98(d), copies of the listed documents are not enclosed as they have been previously cited by or submitted to the Patent and Trademark Office in prior application Serial No. 10/230,874, and because those references cited by the Applicant in that prior application were submitted in Rule-compliant Information Disclosure Statements.

Applicant respectfully requests that the listed documents be considered and made of record in the present case, and that the Examiner initial the spaces on the accompanying Form PTO-1449 to evidence the same.

Respectfully submitted,



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Date: 1-22-2004

Form PTO-1449 (modified)		Atty. Docket No. 102-0075US-3	Serial No. unknown
List of Patents and Publications for Applicant's INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		Applicant Cem Basceri; Gurtej S. Sandhu	
		Filing Date: August 29, 2002	Group: unknown
U.S. Patent Documents <i>See Page Error! Bookmark not defined.</i>	Foreign Patent Documents <i>See Page 1</i>	Other Art <i>See Page 1</i>	

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
	A1	4966646	10/30/1990	Zdeblick			
	A2	5865417	02/02/1999	Harris et al.			
	A3	6062256	05/16/2000	Miller et al.			
	A4	6123107	09/26/2000	Selser et al.			
	A5	6129331	10/10/2000	Henning et al.			
	A6	6149123	11/21/2000	Harris et al.			
	A7	6160243	12/12/2000	Cozad			
	A8	6182603	02/06/2001	Shang et al.			
	A9	6210754	04/03/2001	Lu et al.			
	A10	6237394	05/29/2001	Harris et al.			
	A11	6290491	09/18/2001	Shahvandi et al.			
	A12	09/651037		Mardian			08/30/2000
	A13						
	A14						
	A15						
	A16						
	A17						
	A18						
	A19						
	A20						

EXAMINER:	DATE CONSIDERED:
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U.S. Patent Documents <i>See Page Error! Bookmark not defined.</i>	Foreign Patent Documents <i>See Page 2</i>	Other Art <i>See Page 2</i>	

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
	B1						
	B2						
	B3						
	B4						
	B5						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
	C1	A.K. Henning et al, "Microfluidic MEMS for Semiconductor Processing," IEEE Transactions on Components, Packaging, and Manufacturing Technology B21, pp. 329-37 (1998)
	C2	A.K. Henning, "Microfluidic MEMS," Proceedings: IEEE Aerospace Conference, Paper 4.906 (IEEE Press, Piscataway, NJ, 1998)
	C3	J.S. Fitch et al., "Pressure-Based Mass-Flow Control Using Thermopneumatically-Actuated Microvalves," Proceedings: Solid-State Sensor and Actuator Workshop, pp. 162-65 (Transducers Research Foundation, Cleveland, OH, 1998)
	C4	A.K. Henning et al., "Contamination Reduction Using MEMS-Based, High-Precision Mass Flow Controllers," Proceedings: SEMICON West Symposium on Contamination Free Manufacturing for Semiconductor Processing (SEMI, Mountain View, CA, 1998)
	C5	A.K. Henning, "Liquid and Gas-Liquid Phase Behavior in Thermopneumatically Actuated Microvalves," Proceedings: Micro Fluidic Devices and Systems, Vol. 3515, pp. 53-63 (International Society for Optical Engineering, Bellingham, WA, 1998)
	C6	A.K. Henning et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing," Proceedings: Micromachined Devices and Components, Vol. 3514, pp. 159-170 (International Society for Optical Engineering, Bellingham, WA, 1998)

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Exam. Init.	Ref. Des.	Citation
	C7	A.K. Henning et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing," Proceedings: SEMICON West Workshop on Gas Distribution (SEMI, Mountain View, CA, 1998)
	C8	D. Maillefer et al., "A High-Performance Silicon Micropump for Disposable Drug Delivery Systems," Proceedings of the MEMS 2001 Conference, Interlaken Switzerland, pp. 413-17 (2001)
	C9	R. Bardell et al., "Designing High-Performance Micro-Pumps Based On No-Moving-Parts Valves," ASME—Microelectromechanical Systems (MEMS), DSC-Vol. 62 HTD-Vol. 354, pp. 47-53 (1997)
	C10	A. Olsson, "Valve-Less Diffuser Micropumps" (1998), published at http://www.s3.kth.se/mst/research/dissertations/pdf/andersodoc.pdf .
	C11	Redwood MicroSystems Introduces Semiconductor Grade Products, 07/12/00, published at www.redwoodmicro.com/semicon.html , pages 1 and 2.
	C12	P. Woias, "Micropumps—Summarizing the First Two Decades," Proceedings: SPIE—International Society for Optical Engineering, Vol. 4560, pp. 39-52 (2001)
	C13	A.K. Henning et al., "A Thermopneumatically Actuated Microvalve for Liquid Expansion and Proportional Control," Proceedings: Transducers '97: 1997 International Solid State Sensors and Actuators Conference, pp. 825-28 (IEEE Press, Piscataway, NJ, 1997)
	C14	U.S. Patent Application filed August 23, 2002, inventors Cem Basceri & Gurtej Sandhu, entitled "Reactors Having Gas Distributors and Methods for Depositing Materials Onto Micro-device Workpieces" (Micron Docket 01-1047; U.S. patent application serial number not yet assigned).

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